

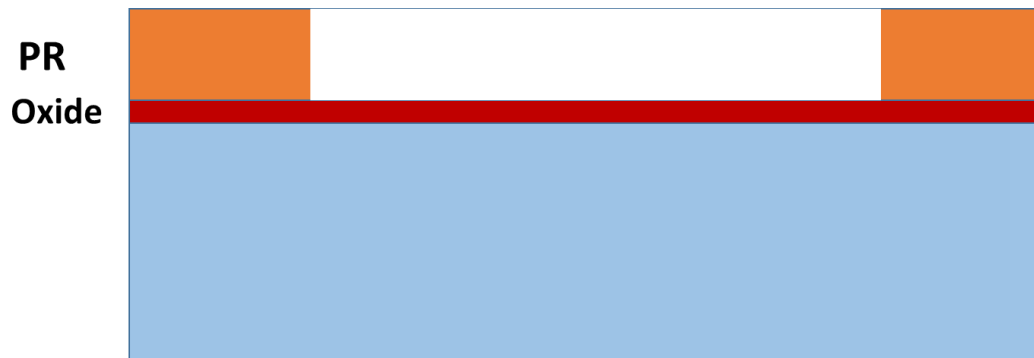
Solution #0 EE/MSE 484

Problem 1:

Step 1: In the n type substrate, Grow thermal oxide;



Step 2: Deposit, expose and develop photoresist; Use mask #1 to pattern the photoresist;



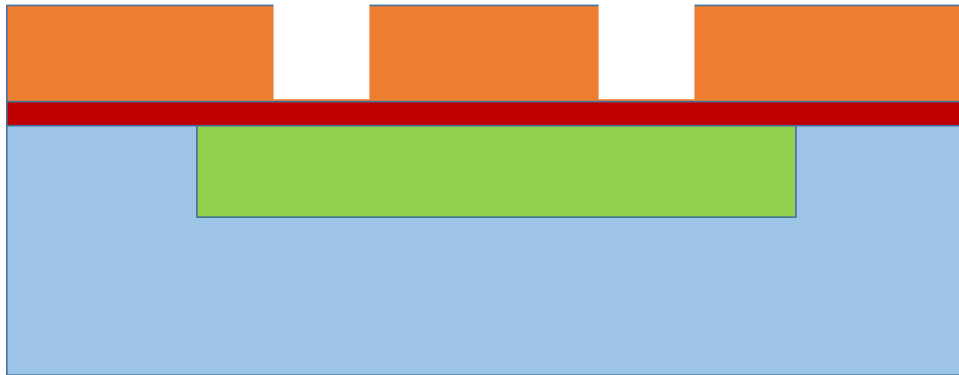
Step 3: Conduct n type implantation using phosphorus;



Step 4: Strip photoresist. Drive in the implanted phosphorus;



Step 4: Deposit, expose and develop photoresist; Use mask #2 to pattern the photoresist;



Step 5: Conduct p type implantation with boron;



Step 6: Strip photoresist. Drive in the implanted boron;

Step 7: Strip oxide and grow a new thermal oxide;

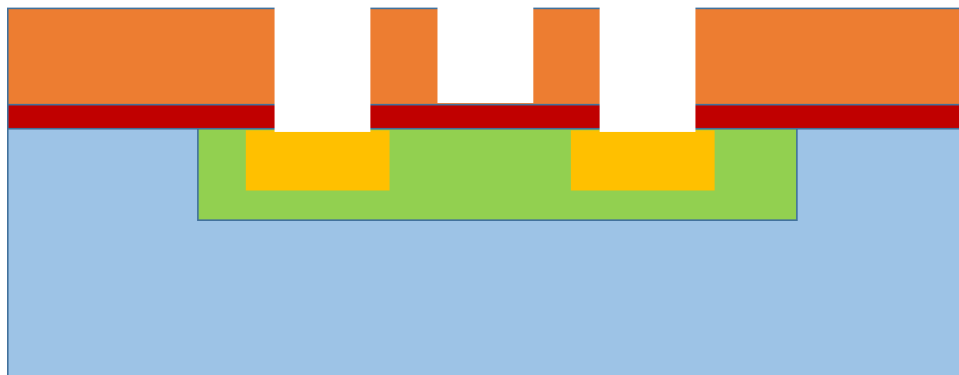
Step 8: Deposit, expose and develop photoresist; Use mask #2 to pattern the photoresist;



Step 9: Etch away the exposed oxide;



Step 10: Deposit, expose and develop photoresist; Use mask #3 to pattern the photoresist;

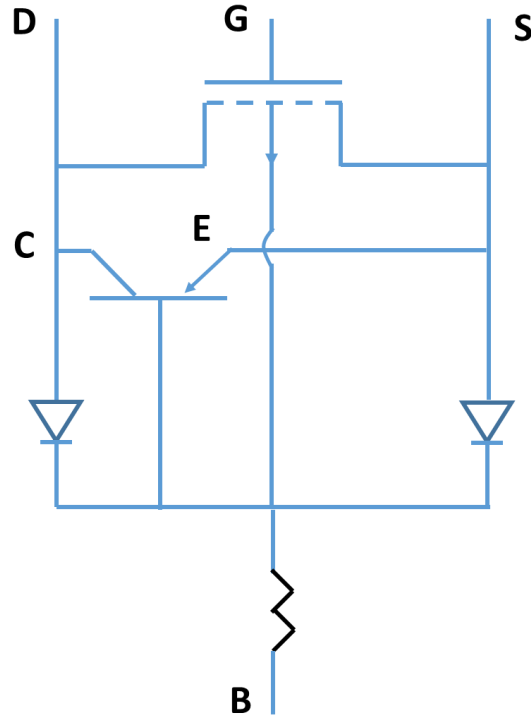


Step 11: Deposit metal and then lift off metal on top of photoresist



Problem 2:

In structure, we have two diodes, one PNP bipolar transistor and one PMOS. The effective circuit is shown below:



Problem 3:

(a) Since $N_A > N_D$, this region should be p type. The hole concentration is:

$$p = \frac{N_A - N_D + \sqrt{(N_A - N_D)^2 + 4n_i^2}}{2}, n = n_i^2/p$$

The result is $p = 2 * 10^{18} \text{ cm}^{-3}, n = 50 \text{ cm}^{-3}$

The mobility is determined by the total doping which is

$$N_T = N_A + N_D = 4 * 10^{18} \text{ cm}^{-3}$$

Based on the plot in the notes we have mobility are

$$\mu_p \sim 100 \text{ cm}^2/\text{Vs}, \quad \mu_n \sim 180 \text{ cm}^2/\text{Vs}$$

(b) Resistivity is

$$\rho = \frac{1}{\sigma} = \frac{1}{q(p\mu_p + n\mu_n)} \sim \frac{1}{1.6 * 10^{-19} * 2 * 10^{18} * 100} = 0.031 \Omega * \text{cm}^{-1}$$

(c) Resistance is

$$R = \frac{\rho L}{S} = \frac{\rho L}{wt} = 0.031 * \frac{2000}{50 * 40 * 10^{-7}} = 313 \text{ k}\Omega$$

Problem 4:

For the p side, $N_T = N_A + N_D \sim 5 * 10^{18} \text{ cm}^{-3}$ the mobility for electron is about $\mu_n = 150 \text{ cm}^2/\text{Vs}$. The diffusivity for the electron is $D_n = \frac{kT}{q} \mu_n = 3.9 \text{ cm}^2/\text{s}$

For the n side, $N_T = N_D = 2 \times 10^{17} \text{ cm}^{-3}$ the mobility for hole is about $\mu_p = 260 \text{ cm}^2/\text{Vs}$. The diffusivity for the electron is $D_p = \frac{kT}{q} \mu_p = 6.7 \text{ cm}^2/\text{s}$

The reversed saturation current is

$$\begin{aligned}
 I_s &= q A n_i^2 \left[\frac{D_n}{N_A W_p} + \frac{D_p}{N_D W_n} \right] \\
 &= 1.6 \times 10^{-19} \times 0.5 \times 10^{-8} \times 10^{20} \times \left[\frac{3.9}{2 \times 10^{18} \times 50 \times 10^{-7}} + \frac{6.7}{2 \times 10^{17} \times 20 \times 10^{-7}} \right] A \\
 &= 1.34 \times 10^{-18} A
 \end{aligned}$$